

AMENDMENT UNDER 37 C.F.R. § 1.116  
EXPEDITED PROCEDURE  
GROUP 2812  
**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q89627

Koichi TERASHIMA, et al.

Appln. No.: 10/544,783

Group Art Unit: 2812

Confirmation No.: 5339

Examiner: Pape A. SENE

Filed: August 8, 2005

For: METHOD FOR FORMING NICKEL SILICIDE FILM, METHOD FOR  
MANUFACTURING SEMICONDUCTOR DEVICE, AND METHOD FOR ETCHING  
NICKEL SILICIDE

**RESPONSE UNDER 37 C.F.R. § 1.116**

**MAIL STOP AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated December 23, 2008, please amend the above-identified application as follows on the accompanying pages. A Petition and payment for a one month Extension of Time are being filed herewith, extending the time period for response to April 23, 2009. This Amendment is therefore timely filed.

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